

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: BIELLAK, STEVE; STOKOWSKI, STANLEY E.; VAEZ-IRAVANI, MEHDI
Assignee: KLA-TENCOR TECHNOLOGIES CORPORATION
Title: SYSTEM AND METHODS FOR A WAFER INSPECTION SYSTEM USING MULTIPLE ANGLES AND MULTIPLE WAVELENGTH ILLUMINATION
Serial No.: ~~09/298,007~~ 09/891,693 Filing Date: June 26, 2001
Examiner: Hoa Q. Pham Group Art Unit: 2877
Docket No.: M-10693 US

BOX FEE AMENDMENT
COMMISSIONER FOR PATENTS
Washington, DC 20231

RESPONSE TO OFFICE ACTION

Dear Sir:

This responds to the Office Action mailed on January 24, 2002, setting a period for response expiring on April 24, 2002. Attached is a Petition for Extension of Time to extend the response period to expire on July 24, 2002.

IN THE SPECIFICATION

On page 9, paragraph 33, line 5, please add after "channel 420." the following: - In other words, illumination channel 416 is at around zero degrees to a normal direction to surface 426. -- The fully amended paragraph is attached hereto.

IN THE CLAIMS:

Please amend the claims 1, 14, 15, 23, 24, 26, 36, 37, 38, and 42, cancel claims 2 and 30, and add claims 46-85 as follows (a marked-up version showing the changes made is attached hereto):

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